## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re	application of:	)
	Mukai et al.	Examiner: Turocy, David P.
Appli	cation No: 09/910,583	) Art Unit: 1792 )
Filed:	July 20, 2001	Atty Docket No.: 005047/DSM/PMD/JW
		Confirmation No.: 1386
For:	METHOD FOR FORMING INTERLAYER	)
	INSULATING FILM IN A	)
	SEMICONDUCTOR MANUFACTURING	)
	METHOD	)
A:-	tant Commissioner For Patents	

## INFORMATION DISCLOSURE STATEMENT

In accordance with Applicant's duty of disclosure, enclosed is a copy of IDS citation Form PTO/SB/08 or PTO-1449, together with copies of the documents cited on that form, except for copies not required to be submitted (e.g., copies of U.S. patents and U.S. published patent applications need not be enclosed). It is respectfully requested that the cited reference be placed in the file.

The submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

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Application No.: 09/910,583 Attv. Docket No.: 005047/DSM/PMD/JW

The Commissioner is authorized to charge any deficiencies or credit any overpayments in connection with this submission to Deposit Account No. 02-2666, and is requested to notify us of same.

Respectfully submitted, BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN, LLP

Date: April 21, 2009 /Justin K. Brask/

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